

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

Date Submitted to PTO: January 5, 2004

ATTY DOCKET NO.
2003-1770SERIAL NO.
NEWAPPLICANT
Kunihiko SAKURAI et al.FILING DATE
January 5, 2004

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AD	AA	6,062,954	5/2000	Izumi	—	—	
	AB	6,156,124	12/2000	Tobin	—	—	
	AC	5,897,426	4/1999	Somekh	—	—	
	AD	6,036,582	3/2000	Aizawa et al.	—	—	
	AE	6,180,020	1/2001	Moriyama et al.	—	—	
	AF	5,655,954	8/1997	Oishi et al.	—	—	
	AG	5,893,795	4/1999	Perlov et al.	—	—	
	AH	5,830,045	11/1998	Togawa et al.	—	—	
AD	AI	5,738,574	4/1998	Tolles et al.	—	—	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
AD	AJ	9-232257	9/1997	JP	—	—	
	AK	97/10613	8/1997	WO	—	—	
	AL	5-285807	11/1993	JP	—	—	
P	AM	197634	4/1908	Germany	—	—	
AD	AN	96/36459	11/1996	WO	—	—	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

AD	AO	U.S. Patent Application No. 09/301,718, filed April 4, 1999, entitled "Method and Apparatus For Polishing Workpiece", by Noburu SHIMIZU et al., located in Group Art Unit 3723.
AD	AP	Kaitoh Tei et al., "Planarization of Device Wafer with Fixed Abrasive Particles (Second Report)" - - Planarization Working Characteristics with Fine Silica Grindstone - -, from the Japan Society for Precision Engineering.
AD	AQ	U.S. Patent Application No. 09/663,417, filed September 15, 2000, entitled "Polishing Apparatus", by Kunihiko SAKURAI et al., located in Group Art Unit 3723.

EXAMINER

Anthony Opini

DATE CONSIDERED

5/11/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

Date Submitted to PTO: January 5, 2004

ATTY DOCKET NO.
2003-1770SERIAL NO.
NEWAPPLICANT
Kunihiko SAKURAI et al.FILING DATE
January 5, 2004

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AD	AA	5,679,059	10/1997	Nishi et al.	—	—	
	AB	4,141,180	2/1979	Gill, Jr. et al.	—	—	
	AC	5,827,110	10/1998	Yajima et al.	—	—	
	AD	5,232,875	8/1993	Tuttle et al.	—	—	
	AE	5,649,854	7/1997	Gill, Jr.	—	—	
	AF	5,562,524	10/1996	Gill, Jr.	—	—	
	AG	5,329,732	7/1994	Karlsrud et al.	—	—	
	AH	5,554,064	9/1996	Brievogel et al.	—	—	
AD	AI	5,885,138	3/1999	Okumura et al.	—	—	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
AD	AJ	82/03038	9/1982	WO	—	—	
	AK	874 309 A1	10/1998	Europe	—	—	
	AL	9-232257	9/1997	JP	—	—	
	AM	7-135192	5/1995	JP	—	—	
AD	AN	8-64562	3/1996	JP	—	—	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

AD	AO	U.S. Patent Application No. 09/341,882, filed September 8, 1999, entitled "Polishing Apparatus", by Seiji KATSUOKA et al., located in Group Art Unit 3723.
AD	AP	U.S. Patent Application No. 09/518,958, filed March 3, 2000, entitled "Polishing Apparatus", by Kunihiko SAKURAI et al., located in Group Art Unit 3723, a C-I-P of application Serial No. 09/476,905, filed January 3, 2000.
	AQ	

EXAMINER

Anthony Djini

DATE CONSIDERED

5/11/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

Date Submitted to PTO: January 5, 2004

ATTY DOCKET NO.
2003-1770SERIAL NO.
NEWAPPLICANT
Kunihiko SAKURAI et al.FILING DATE
January 5, 2004

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AD	AA	5,616,063	4/1997	Okumura et al.	—	—	
	AB	3,906,678	9/1975	Roth	—	—	
	AC	3,913,271	10/1975	Boettcher	—	—	
	AD	5,718,618	2/1998	Guckel et al.	—	—	
	AE	5,989,107	11/1999	Shimizu et al.	—	—	
	AF	5,618,227	4/1997	Tsutsumi et al.	—	—	
	AG	3,659,386	5/1972	Goetz et al.	—	—	
	AH	4,680,893	7/1987	Cronkhite et al.	—	—	
AD	AI	5,551,986	9/1996	Jain	—	—	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
AD	AJ	5-285807	11/1993	JP	—	—		
	AK	807 492 A2	11/1997	Europe	—	—		
	AL	10-256201	9/1998	JP	—	—		
	AM	5-74749	3/1993	JP	—	—		
AD	AN	2-208931	8/1990	JP	—	—		

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

	AO	
	AP	
	AQ	
EXAMINER	Anthony Ojini	
	DATE CONSIDERED	5/11/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

Date Submitted to PTO: January 5, 2004

ATTY DOCKET NO.
2003-1770SERIAL NO.
NEWAPPLICANT
Kunihiko SAKURAI et al.FILING DATE
January 5, 2004

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AD	AA	5,951,373	9/1999	Shendon et al.	—	—	
	AB	5,839,947	11/1998	Kimura et al.	—	—	
	AC	6,050,884	4/2000	Togawa et al.	—	—	
	AD	6,293,855	9/2001	Yoshida et al.	—	—	
AD	AE	5,498,199	3/1996	Karlsrod et al.	—	—	
	AF						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
AD	AG	4-69147	3/1992	JP	—	—		
	AH	0 517 594	12/1992	Europe	—	—		
	AI	0 684 634	11/1995	Europe	—	—		
	AJ	2-267950	11/1990	JP	—	—		
	AK	64-42823	2/1989	JP	—	—		
	AL	0761387A1	3/1997	EP	—	—		
	AM	0807492A2	11/1997	EP	—	—		
	AN	0928662A2	7/1999	EP	—	—		
AD	AO	0793261A2	9/1997	EP	—	—		

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

	AP	
	AQ	

EXAMINER

Anthony Djini

DATE CONSIDERED

5/11/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.